Introduction to MEMS

Course Code:

ME 462

Course Type:

Area Elective

Credits:

3

Theoric:

3

Practice:

0

Laboratory Hour:

0

ECTS:

5

Course Language:

English

Course Content:

An overview of microfabrication methods: Thin-film deposition, lithography, oxidation, bulk and surface micromachining. MEMS (microelectromechanical systems) foundry processes. Review of basic MEMS governing equations in mechanical, electrical and thermal domain. Design, analysis and characterization of basic MEMS devices.